



# AZ<sup>®</sup> MiR<sup>™</sup> 701 Photoresist

Page 1 of 2

## Product Description

AZ<sup>®</sup> MiR<sup>™</sup> Series photoresists are fast, cost effective resists designed for replacement of older mid-range production resists. The AZ MiR series resists work well in both surfactated and non-surfactated TMAH developers using standard process conditions.

AZ MiR 701 photoresist is designed for production use at 0.30μm to 0.40μm CDs.

## Features

- High Throughput
- Cross over Exposure Capable
- Wide process latitude
- Thermal Stability

## Benefits

i-line DTP ~ 190mJ/cm<sup>2</sup>

Mix/match with i-line, g-line, or broadband

Production processing 0.30μm - 0.40μm features

1.4μm DOF @ 0.35μm

1.4μm DOF @ 0.30μm

>125°C dependent on process conditions

## Standard Process Conditions

Coat : 0.974μm Emax thickness

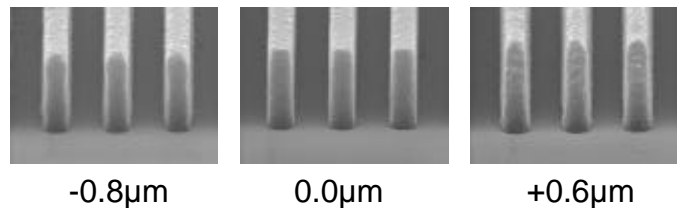
SB : 90°C for 60sec (proximity)

Expo : ASML/250 @ NA=0.60

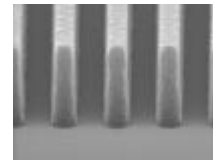
PEB : 110°C for 60sec (proximity)

Develop : AZ<sup>®</sup> 300MIF for 60sec  
single puddle @ 23°C

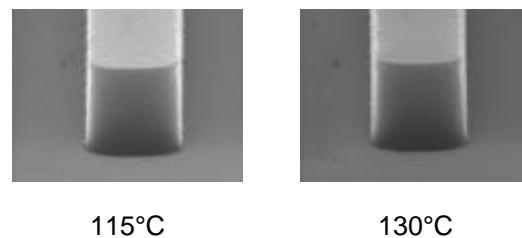
## DOF @ 0.35μm Feature



## 0.30μm Features @ 180mJ



## Thermal Stability 1μm Features



## Modelling Parameters

### Refractive Index

	365nm	436nm
n	1.7039	1.6917
k	0.0214	0.0189

### Dills :

$$A = 0.7090 \quad B = 0.0342 \quad C = 0.0220$$

### Cauchies :

unbleached

$$A = 1.6104 \quad B = 0.00505\mu\text{m}^2 \quad C = 0.00171\mu\text{m}^4$$

bleached

$$A = 1.6057 \quad B = 0.00673\mu\text{m}^2 \quad C = 0.00094\mu\text{m}^4$$



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Page 2 of 2

## Storage

Keep in sealed original containers away from oxidants, sparks, and open flame. Protect from light and heat. Keep refrigerated. Recommended storage temperature of 45°F. Empty container may contain harmful residue and/or vapors. Dispose of appropriately.

## Equipment Compatibility

AZ MiR 701 photoresist is compatible with all commercially available wafer and photomask processing equipment. Recommended materials of construction include stainless steel, glass, ceramic, PTFE, polypropylene, and HDPE.

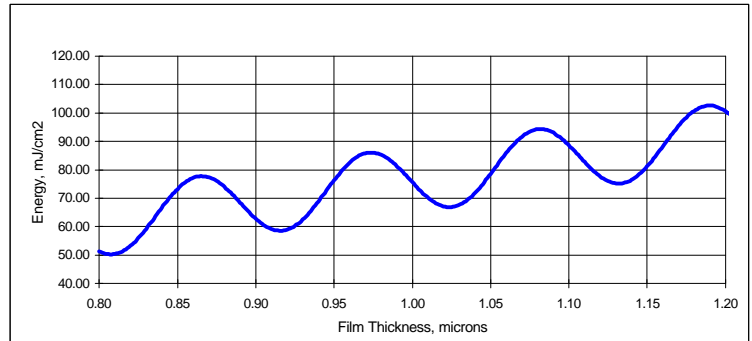
## Solvent Safety

AZ MiR 701 photoresist is formulated with a mixture of PGMEA and EL safer solvents. We recommend AZ EBR 70/30 as a compatible solvent for EBR processing, resist cleaning, basic resist stripping and re-work.

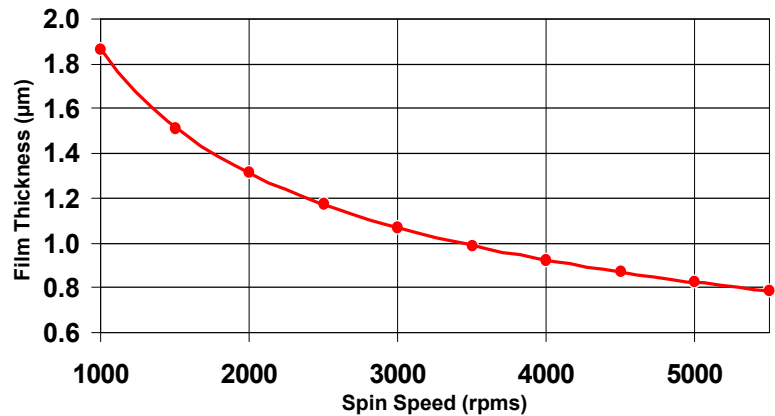
## Handling Precautions / First Aid

Refer to current Material Safety Data Sheet (MSDS) for detailed information prior to handling.

i-line Swing Curve



Spin Speed Curve on 150mm wafer



Bossung plot 0.35µm isolated lines

